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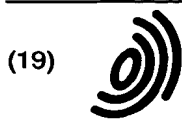
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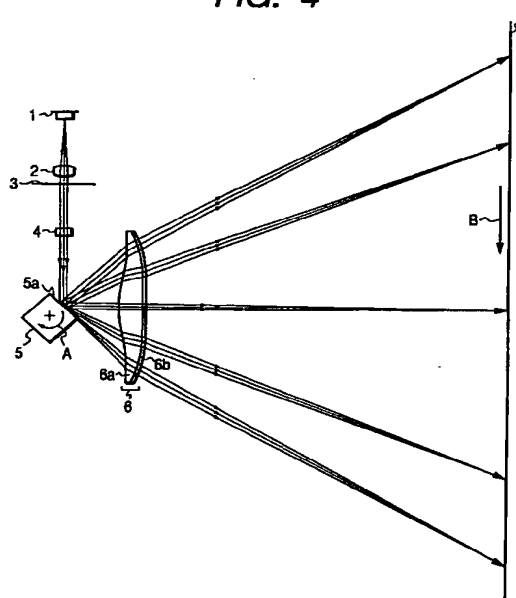
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(54) Corrected scanning optical apparatus

(57) A scanning optical apparatus includes a semiconductor laser as a light source, a deflector for deflecting a light beam emitted from the semiconductor laser, and optical element for directing the light beam emitted from the semiconductor laser to a surface to be scanned. The optical element includes a refracting portion and a diffracting portion, wherein changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the optical element.

FIG. 4



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Descripti n

BACKGROUND OF THE INVENTION

5 Field of the Invention

This invention relates to a scanning optical apparatus, and particularly to a scanning optical apparatus suitable for use in an apparatus such as a laser beam printer (LBP) having an electrophotographic process or a digital copying apparatus designed to deflect a light beam emitted from light source means comprising a semiconductor laser by a
10 deflecting element, and optically scan a surface to be scanned through a scanning optical element (an imaging element) having the $f\theta$ characteristic to thereby record image information.

Related Background Art

15 In a scanning optical apparatus used in a laser beam printer, a digital copying apparatus or the like, a light beam optically modulated and emitted from light source means in conformity with an image signal is periodically deflected by a light deflector comprising, for example, a rotatable polygon mirror, and is converged into a spot-like shape on the surface of a photosensitive recording medium (a photosensitive drum) by a scanning optical element (an imaging element) having the $f\theta$ characteristic, and the surface is optically scanned to thereby effect image recording.

20 As the scanning optical apparatus used in such a laser beam printer (LBP) or the like, a requirement for an apparatus which is strong against any fluctuation of the environment and moreover is suitable for highly minute printing has heightened with a reduction in price and compactness of the LBP.

Fig. 1 of the accompanying drawings is a schematic view of the essential portions of a scanning optical apparatus of this kind according to the prior art.

25 In Fig. 1, a divergent light beam emitted from light source means 21 is substantially collimated by a collimator lens 22, and this light beam (the quantity of light) is limited by a stop 23 and enters a cylindrical lens 24 having predetermined refractive power only in a sub-scanning direction. In the main scanning cross-section of the parallel light beam which has entered the cylindrical lens 24, the light beam emerges therefrom intactly as a parallel light beam. Also, in the sub-scanning cross-section, the light beam converges and is formed as a substantially linear image on the deflecting surface (reflecting surface) 25a of a light deflector 25 comprising a rotatable polygon mirror. Here, the main scanning cross-section refers to a light beam cross-section formed with time by a light beam deflected and reflected by the
30 deflecting surface of the light deflector. Also, the sub-scanning cross-section refers to a cross-section containing the optical axis of an $f\theta$ lens and orthogonal to the main scanning cross-section.

The light beam deflected by the deflecting surface 25a of the light deflector 25 is directed to a photosensitive drum surface 28 as a surface to be scanned through a scanning optical element ($f\theta$ lens) 26 having the $f\theta$ characteristic, and the light deflector 25 is rotated in the direction of arrow A, whereby the photosensitive drum surface 28 is optically scanned in the direction of arrow B. Thereby, image recording is effected on the photosensitive drum surface 28 which is a recording medium.

In recent years, as regards the scanning optical element ($f\theta$ lens) in the scanning optical apparatus of this kind, one
40 using a plastic lens formed of a plastic material has become the mainstream from the requirements for a low price and compactness. However, the plastic lens has the nature that its refractive index varies with the fluctuation (temperature fluctuation) of its use environment and therefore, in a scanning optical apparatus using an $f\theta$ lens comprising the plastic lens, changes in the magnification in the main scanning direction and changes in focus due to the fluctuation of the environment are caused.

45 Fig. 2 of the accompanying drawings is a cross-sectional view (main scanning cross-sectional view) of the essential portions of a comparative example of the scanning optical apparatus in the main scanning direction thereof for illustrating such problem, and Table 1 below shows the optical arrangement and the aspherical coefficient of the $f\theta$ lens in the comparative example. Fig. 3 of the accompanying drawings is an illustration showing the curvature of image field, the aberration of distortion and image height deviation in the main scanning direction of this scanning optical apparatus,
50 and the solid lines indicate the characteristics at room temperature (25°C), and the dotted lines indicate the characteristics when a temperature rise to 50°C arose. In Fig. 2, the same elements as those shown in Fig. 1 are given the same reference characters.

Table 1

Design Example of Scanning Optical Apparatus

| | | | | surface shape of f θ lens | |
|--|---------------------------|-------|------|----------------------------------|----------------|
| | | | | first surface | second surface |
| wavelength used | $\lambda(\text{nm})$ | 780 | R | 5.35941e+01 | 2.04585e+02 |
| refraction index of f θ lens | n | 1.525 | Ks | -1.85041e+01 | -3.19655e+02 |
| incident angle in polygon | θ_i | -90.0 | B4s | -4.01467e+06 | -5.67674e-06 |
| max. emergence angle in polygon | θ_{max} | 45.0 | B6s | 1.97617e-10 | 1.13298e-09 |
| distance between polygon and f θ lens | e | 21.3 | B8s | 3.18251e-13 | -1.08244e-12 |
| center thickness of f θ lens | d | 8.0 | B10s | -4.34340e-17 | 3.75204e-17 |
| distance between f θ lens and scanned surface | Sk | 128.2 | Ke | -1.85041e+01 | -3.19655e+02 |
| f θ coefficient | f | 136.0 | B4e | -6.38051e-06 | -7.32456e-06 |
| polygon | $\phi 20$, 4 surfaces | | B6e | -5.04862e-10 | 4.21805e-10 |
| In the shape of f θ lens, suffix s indicates laser side, and suffix e indicates a side opposite to laser side. | | | B8e | 2.89411e-13 | -1.75629e-12 |
| | | | B10e | 1.05151e-15 | 5.30015e-17 |
| | | | | BOE Phase term | |
| | | | | first surface | second surface |
| | | | C2 | - | - |
| | | | C4 | - | - |
| | | | C6 | - | - |
| | | | C8 | - | - |

As can be seen from Fig. 3, when an f θ lens comprising a plastic lens is used, the focus and magnification in the main scanning direction are changed greatly by temperature rise, and particularly in a scanning optical apparatus for effecting highly minute printing, the changes in the focus and magnification due to this environmental fluctuation (temperature fluctuation) pose a problem.

Also, from U.S. Patent No. 5,486,694, there is known a scanning optical apparatus in which a light beam emitted from light source means is deflected by a deflecting element, and the deflected light beam is imaged on a surface to be scanned through a scanning optical element having a refracting portion and a diffracting portion to thereby scan the surface to be scanned.

In the scanning optical element disclosed in this U.S. Patent No. 5,486,694, however, no consideration is paid to the environmental fluctuations.

SUMMARY OF THE INVENTION

It is an object of the present invention to provide a scanning optical apparatus for correcting changes in focus in the

main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus by the characteristic of optical means having a refracting portion and a diffracting portion, whereby which is strong against the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of a semiconductor laser which is light source means) and moreover is suitable for highly minute printing and compact.

It is also an object of the present invention to provide a scanning optical apparatus for correcting changes in focus and changes in magnification in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus by the characteristic of a scanning optical element having a refracting portion and a diffracting portion, whereby which is strong against the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of a semiconductor laser which is light source means) and moreover is suitable for highly minute printing and compact.

The scanning optical apparatus of the present invention comprises:

light source means comprising a semiconductor laser;

a deflecting element for deflecting a light beam emitted from the light source means; and

optical means having a refracting portion and a diffracting portion and for directing the light beam emitted from the light source means onto a surface to be scanned;

characterized in that changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the optical means.

Particularly, the scanning optical apparatus is characterized in that the environmental fluctuations are temperature fluctuation and a wavelength fluctuation of the semiconductor laser, and the characteristic is the power ratio between the refracting portion and diffracting portion of the optical means.

Also, the scanning optical apparatus is characterized in that when the optical means is a scanning optical element for directing the light beam deflected by the deflecting element onto the surface to be scanned, changes in magnification and changes in focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the scanning optical element.

Particularly, the scanning optical apparatus is characterized in that when the powers of the refractive portion and the diffracting portion of the scanning optical element are ϕL and ϕD , respectively, the condition that

$$1.0 \leq \phi L / \phi D \leq 2.6$$

is satisfied,

the refracting portion comprises a single lens, the diffracting portion comprises a diffracting optical element, the diffracting optical element is added to at least one of the both lens surfaces of the single lens,

the material of the single lens is a plastic material,

the both lens surfaces of the single lens in the main scanning direction comprise an aspherical shape,

the single lens differs in refractive power between the main scanning direction and the sub-scanning direction,

the diffracting optical element is a binary optical element comprising a staircase-like diffraction grating,

or the diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating, and the power ratio between the refracting portion and the diffracting portion of the scanning optical element satisfies the condition within the range from the on-axis to the off-axis.

Also, the scanning optical apparatus is characterized in that the optical means is an anamorphic optical element having a diffracting portion and for imaging the light beam emitted from the light source means into a linear shape long in the main scanning direction on the deflecting surface of the deflecting element, and a scanning optical element having a refracting portion for directing the light beam deflected by the deflecting element onto the surface to be scanned, and

changes in focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the anamorphic optical element and the scanning optical element.

Particularly, the scanning optical apparatus is characterized in that the characteristic is the power ratio between the diffracting portion of the anamorphic optical element and the refracting portion of the scanning optical element,

the anamorphic optical element comprises a cylindrical lens, the diffracting portion comprises a diffracting optical element,

the diffracting optical element is added to at least one of the both lens surfaces of the cylindrical lens,
 the scanning optical element is a single lens, the material of the single lens is a plastic material,
 the both lens surfaces of the single lens in the main scanning direction comprise an aspherical shape,
 the single lens differs in refractive power between the main scanning direction and the sub-scanning direction,
 5 the diffracting optical element is a binary optical element comprising a staircase-like diffraction grating, or
 the diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.

Also, the scanning optical apparatus is characterized in that the optical means is a converting optical element having a diffracting portion and for converting the light beam emitted from the light source means into a substantially parallel light beam, and a scanning optical element having a refracting portion for directing the light beam deflected by the
 10 deflecting element onto the surface to be scanned, and

changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the converting optical element and the scanning optical element.
 15

Particularly, the scanning optical apparatus is characterized in that the characteristic is the power ratio between the diffracting portion of the converting optical element and the refracting portion of the scanning optical element,

the converting optical element comprises a collimator lens having positive refractive power,
 the diffracting portion comprises a diffracting optical element,
 the diffracting optical element is added to at least one of the both lens surfaces of the collimator lens,
 the scanning optical element is a single lens, the material of the single lens is a plastic material,
 the both lens surfaces of the single lens in the main scanning direction comprise an aspherical shape,
 25 the single lens differs in refractive power between the main scanning direction and the sub-scanning direction,
 the diffracting optical element is a binary optical element comprising a staircase-like diffraction grating, or
 the diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.

BRIEF DESCRIPTION OF THE DRAWINGS

Fig. 1 is a schematic view of the essential portions of a scanning optical apparatus according to the prior art.

Fig. 2 is a cross-sectional view of the essential portions of the scanning optical apparatus according to the prior art in the main scanning direction.

Fig. 3 shows curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in the scanning optical apparatus according to the prior art.

Fig. 4 is a cross-sectional view of the essential portions of Embodiment 1 of the present invention in the main scanning direction.

Fig. 5 shows curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in Embodiment 1 of the present invention.

Fig. 6 is a cross-sectional view of the essential portions of Embodiment 2 of the present invention in the main scanning direction.

Fig. 7 shows curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in Embodiment 2 of the present invention.

Fig. 8 is a cross-sectional view of the essential portions of Embodiment 3 of the present invention in the main scanning direction.

Fig. 9 shows curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in Embodiment 3 of the present invention.

Fig. 10 is a cross-sectional view of the essential portions of Embodiment 4 of the present invention in the main scanning direction.

Fig. 11 shows curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in embodiment 4 of the present invention.

Fig. 12 is a cross-sectional view of the essential portions of Embodiment 5 of the present invention in the main scanning direction.

DESCRIPTION OF THE PREFERRED EMBODIMENTS

Fig. 4 is a cross-sectional view (main scanning cross-sectional view) of the essential portions of a scanning optical apparatus according to Embodiment 1 of the present invention for use in a laser beam printer in the main scanning

direction.

In Fig. 4, reference numeral 1 designates light source means comprising, for example, a semiconductor laser. Reference numeral 2 denotes a collimator lens which converts a divergent light beam emitted from the light source means 1 into a parallel light beam. Reference numeral 3 designates an aperture stop which limits the passing light beam (the quantity of light). Reference numeral 4 denotes a cylindrical lens (cylinder lens) which has predetermined refractive power only in a sub-scanning direction perpendicular to the plane of the drawing sheet of Fig. 4, and which images the light beam passed through the aperture stop 3 as a substantially linear image in a sub-scanning cross-section on the deflecting surface 5a of a light deflector 5 to be described below.

Reference numeral 5 denotes a light deflector comprising, for example, a polygon mirror (rotatable polygon mirror) as a deflecting element, and being rotated at a predetermined speed in the direction of arrow A by driving means (not shown) such as a motor.

Reference numeral 6 designates a scanning optical element having the $f\theta$ characteristic and having a refracting portion 6a and a diffracting portion 6b. The refracting portion 6a comprises a single lens ($f\theta$ lens) formed of a plastic material, and the both lens surfaces of the single lens 6a in the main scanning direction comprise an aspherical shape. Also, the single lens 6a differs in refractive power between the main scanning direction and the sub-scanning direction. The diffracting portion 6b comprises a diffracting optical element, and comprises, for example, a binary diffracting optical element comprising a staircase-like diffraction grating by photoetching, or a Fresnel-like diffracting optical element comprising a sawtooth-like diffraction grating by surface cutting. In the present embodiment, the diffracting optical element 6b is added to at least one (the surface to be scanned side) of the both lens surfaces of the single lens 6a, and design is made such that the power (refractive power) ratio between the refracting portion 6a and the diffracting portion 6b is all within the range of expression (1) which will be described later from the on-axis toward the off-axis. The scanning optical element 6 causes a light beam based on image information deflected by the light deflector 5 to be imaged on a photosensitive drum surface 8 which is a recording medium and a surface to be scanned, and corrects the surface inclination of the deflecting surface of the light deflector 5.

In the present embodiment, a divergent light beam emitted from the semiconductor laser 1 is converted into a substantially parallel light beam by the collimator lens 2, and this light beam (the quantity of light) is limited by the aperture stop 3 and enters the cylindrical lens 4. The light beam which has entered the cylindrical lens 4 intactly emerges therefrom in the main scanning cross-section. Also, in the sub-scanning cross-section, the light beam converges and is imaged as a substantially linear image (a linear image long in the main scanning direction) on the deflecting surface 5a of the light deflector 5. The light beam deflected by the deflecting surface 5a of the light deflector 5 is then directed onto the photosensitive drum surface 8 through the scanning optical element 6, and this light deflector 5 is rotated in the direction of arrow A to thereby optically scan the photosensitive drum surface 8 in the direction of arrow B. Thereby, image recording is effected on the photosensitive drum surface 8 which is a recording medium.

The shapes of the single lens ($f\theta$ lens) 6a constituting the scanning optical element 6 in the present embodiment and the diffracting optical element 6b added to that lens surface of the single lens 6a which is located at a side of the surface 8 to be scanned are as follows:

(1) single lens ... an aspherical shape in which the main scanning direction can be represented by a function x up to 10th order.

When the point of intersection between the single lens 6a and the optical axis is defined as the origin, and the direction of the optical axis is defined as the x -axis, the axis orthogonal to the optical axis in the main scanning plane is defined as the y -axis, and the axis orthogonal to the optical axis in the sub-scanning plane is defined as the z -axis,

$$x = \frac{Y^2/R}{1+(1-K)(Y/R)^2} + B_4 Y^4 + B_6 Y^6 + B_8 Y^8 + B_{10} Y^{10}$$

(where R is the radius of curvature, and K , B_4 , B_6 , B_8 and B_{10} are aspherical surface coefficients)

(2) diffracting optical element ... a diffracting surface in which the main scanning direction is represented by a phase function w up to the 8th order is represented by the following expression:

$$w = C_2 Y^2 + C_4 Y^4 + C_6 Y^6 + C_8 Y^8$$

Consider here a case where the temperature of the scanning optical apparatus has risen e.g. by dt . By this temperature rise, the refractive index n of the refracting portion 6a of the scanning optical element is changed by dn/dt , and a change $d\phi_1$ in power (refractive power) resulting therefrom is:

$$d\phi_L = \phi_L / (n-1) \times dn/dt$$

n: refractive index of the refracting portion 6a

ϕ_L : power of the refracting portion 6a

On the other hand, by the temperature rise, the oscillation wavelength λ of the semiconductor laser 1 is also changed by $d\lambda/dt$, and changes $d\phi_L$ and $d\phi_D$ in the power (refractive power) of the refracting portion 6a and the diffracting portion 6b resulting therefrom are:

$$d\phi_L = -\phi_L / (170 \times v_L) \times d\lambda/dt$$

$$d\phi_D = -\phi_D / (170 \times v_D) \times d\lambda/dt$$

v_L : Abbe's number of the refracting portion 6a

v_D : Abbe's number of the diffracting portion 6b

ϕ_L : power of the refracting portion 6a

ϕ_D : power of the diffracting portion 6b

Here, to suppress the changes in magnification and focus in the main scanning direction caused by environmental fluctuations, it is necessary to satisfy the following expression:

$$d\phi_L + d\phi_L + d\phi_D = 0$$

Also, the Abbe's number v_D of the diffracting portion 6b and the amount of change resulting from the temperature rise are defined, for example, as follows:

$$v_D = -3.453$$

$$dn/dt = -1.2E-4/^{\circ}C$$

$$d\lambda/dt = 0.255 \text{ nm}/^{\circ}C$$

$$d\phi_L + d\phi_L + d\phi_D = 0$$

$$\phi_L / (n-1) dn/dt - (\phi_L / (170 v_L) + \phi_D / (170 v_D)) d\lambda/dt = 0$$

$$(1.2E-4/(n-1) + 1.5E-3/v_L) \phi_L = 4.34E-4 \phi_D$$

Here, when the values the refractive index and Abbe's number of the refracting portion 6a may assume are taken into consideration,

$$1.0 \leq \phi_L / \phi_D \leq 2.6, \quad (1)$$

ϕ_L : power of the refracting portion 6a

ϕ_D : power of the diffracting portion 6b

and there can be derived the power ratio between the refracting portion 6a and the diffracting portion 6b of the scanning optical element 6 necessary to correct the changes in magnification and focus in the main scanning direction caused by environmental fluctuations (the fluctuation of temperature and the fluctuation of the wavelength of the semiconductor laser 1).

Conditional expression (1) relates to the ratio between the power of the refracting portion 6a constituting the scanning optical element 6 and the power of the diffracting portion 6b also constituting the scanning optical element 6, and if conditional expression (1) is deviated from, it will become difficult to correct the changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus, and this is not preferable.

Table 2 below shows the optical arrangement in the present embodiment, the aspherical surface coefficient of the f θ lens 6a and the phase term of the diffracting optical element (BOE) 6b.

Table 2

Design Example of Scanning Optical Apparatus

| | | | | surface shape of fθ lens | |
|--|--------------------|-------|------|---------------------------------------|----------------|
| | | | | first surface | second surface |
| wavelength used | λ(nm) | 780 | R | 7.93998e+01 | 2.20976e+02 |
| refraction index of fθ lens | n | 1.525 | Ks | -1.97428e+01 | -1.09646e+02 |
| incident angle in polygon | θi | -90.0 | B4s | -4.04006e-06 | -4.41224e-06 |
| max. emergence angle in polygon | θmax | 45.0 | B6s | 1.40143e-09 | 9.51528e-10 |
| distance between polygon and fθ lens | e | 27.3 | B8s | -6.54101e-13 | -2.67361e-13 |
| center thickness of fθ lens | d | 7.7 | B10s | 1.56835e-16 | -5.85889e-17 |
| distance between fθ lens and scanned surface | Sk | 131.1 | Kc | -1.67052e+01 | -8.60770e+01 |
| fθ coefficient | f | 136.0 | B4e | -4.36069e-06 | -4.44281e-06 |
| polygon | φ20, 4 surfaces | | B6e | 1.47141e-09 | 9.34793e-10 |
| In the shape of fθ lens, suffix s indicates laser side, and suffix e indicates a side opposite to laser side. | | | B8e | -6.14682e-13 | -3.84409e-13 |
| | | | B10e | 1.79142e-16 | 3.57417e-17 |
| | | | | BOE Phase term (wavelength 780 nm) | |
| | | | | first surface | second surface |
| | | | C2 | - | -1.5778E-03 |
| | | | C4 | - | 4.1480E-07 |
| | | | C6 | - | -3.7020E-10 |
| | | | C8 | - | 5.2146E-14 |

Embodiment 1

In this embodiment, the power ratio between the refracting portion 6a and the diffracting portion 6b of the scanning optical element 6 is

$$\phi L / \phi D = 1.369,$$

whereby conditional expression (1) is satisfied. Fig. 5 is an illustration showing curvature of image field, aberration of distortion (fθ characteristic) and image height deviation in the main scanning direction before and after temperature rise in the present embodiment, and the solid lines indicate the characteristics at room temperature (25°C) and the dotted lines indicate the characteristics when temperature has risen by 25°C and has reached 50°C. It is seen from Fig. 5 that there is little or no change in focus and magnification in the main scanning direction before and after the temperature rise (in Fig. 5, the difference between before and after the temperature rise is minute and therefore the graphs before and after the temperature rise overlap each other).

In the present embodiment, as described above, the scanning optical element 6 is comprised of the refracting portion 6a comprising a lens and the diffracting portion 6b comprising a diffracting optical element, and the power ratio between the refracting portion 6a and the diffracting portion 6b is set to a suitable value so as to satisfy the above-mentioned conditional expression (1), whereby changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus (temperature fluctuation and the wavelength fluctuation of the semiconductor laser) are corrected by the changes in the power of the refracting portion 6a and the diffracting portion 6b. Thereby, according to the present embodiment, a scanning optical apparatus which is strong against the environmental fluctuations and moreover is suited for highly minute printing is obtained compactly and inexpensively.

Fig. 6 is a cross-sectional view (main scanning cross-sectional view) of the essential portions of Embodiment 2 of the present invention in the main scanning direction. In Fig. 6, the same elements as those shown in Fig. 4 are given the same reference numerals.

The difference of this embodiment from the aforescribed Embodiment 1 are that the material of the refracting portion (f θ lens) 36a of a scanning optical element 36 is a plastic material of high refractive index as compared with that in Embodiment 1 and that correspondingly thereto, the power ratio of the refracting portion 36a and the diffracting portion (diffracting optical element) 36b of the scanning optical element 36 is made to differ. In the other points, the construction and optical action of the present embodiment are substantially similar to those of the aforescribed Embodiment 1, whereby there is obtained a similar effect.

Table 3 below shows the optical arrangement in the present embodiment, the aspherical surface coefficient of the f θ lens 36a and the phase term of the diffracting optical element (BOE) 36b.

Table 3

Design Example of Scanning Optical Apparatus

| | | | | surface shape of fθ lens | |
|--|--------------------|-------|------|---------------------------------------|----------------|
| | | | | first surface | second surface |
| wavelength used | λ(nm) | 780 | R | 1.07911e+02 | 3.18395e+02 |
| refraction index of fθ lens | n | 1.802 | Ks | -2.28102e+01 | -9.46473e+01 |
| incident angle in polygon | θi | -90.0 | B4s | -4.66119e-06 | -4.71285e-06 |
| max. emergence angle in polygon | θmax | 45.0 | B6s | 1.59106e-09 | 1.24842e-09 |
| distance between polygon and fθ lens | c | 27.3 | B8s | -4.98547e-13 | -3.41971e-13 |
| center thickness of fθ lens | d | 7.8 | B10s | 1.13098e-16 | 1.39279e-17 |
| distance between fθ lens and scanned surface | Sk | 131.3 | Ke | -1.89458e+01 | -7.85820e+01 |
| fθ coefficient | f | 136.0 | B4e | -4.90287e-06 | -4.67721e-06 |
| polygon | φ20, 4 surfaces | | B6e | 1.41254e-09 | 9.61537e-10 |
| In the shape of fθ lens, suffix s indicates laser side, and suffix e indicates a side opposite to laser side. | | | B8e | -4.39029e-13 | -2.50060e-13 |
| | | | B10e | 1.10119e-16 | -2.65806e-17 |
| | | | | BOE Phase term (wavelength 780 nm) | |
| | | | | first surface | second surface |
| | | | C2 | - | -1.2257E-03 |
| | | | C4 | - | 4.5423E-07 |
| | | | C6 | - | -4.5625E-10 |
| | | | C8 | - | 1.1027E-13 |

Embodiment 2

In the present embodiment, the power ratio between the refracting portion 36a and the diffracting portion 36b of the scanning optical element 36 is

$$\phi L / \phi D = 2.038$$

to thereby satisfy conditional expression (1). Fig. 7 is an illustration showing curvature of image field, aberration of distortion (f θ characteristic) and image height deviation in the main scanning direction before and after temperature rise in the present embodiment, and the solid lines indicate the characteristics at room temperature (25°C) and the dotted lines indicate the characteristics when temperature has risen by 25°C and has reached 50°C. It is seen from Fig. 7 that there is little or no change in the focus and magnification in the main scanning direction before and after the temperature rise.

In the present embodiment, even if as described above, the material of the refracting portion (f θ lens) 36a is a mate-

rial of high refractive index as compared with that in Embodiment 1, the power ratio between the refracting portion 36a and the diffracting portion 36b is set to a suitable value so as to satisfy the aforementioned conditional expression (1), whereby as in Embodiment 1, changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of the semiconductor laser) of the scanning optical apparatus can be corrected by changes in the power of the refracting portion 36a and the diffracting portion 36b. Also, in the present embodiment, the refracting portion (f θ lens) 36a is constructed by the use of a material of high refractive index and therefore, the center thickness of the refracting portion 36a can be made small, whereby a further reduction in price can be achieved.

Fig. 8 is a cross-sectional view (main scanning cross-sectional view) of the essential portions of Embodiment 3 of the present invention in the main scanning direction. In Fig. 8, the same elements as these shown in Fig. 4 are given the same reference numerals.

The differences of the present embodiment from the aforescribed Embodiment 1 are that the material of the refracting portion (f θ lens) 56a of a scanning optical element 56 is a plastic material of low refractive index as compared with that in Embodiment 1, and that correspondingly thereto, the power ratio between the refracting portion 56a and the diffracting portion (diffracting optical element) 56b of the scanning optical element 56 is made to differ. In the other points, the construction and optical action of the present embodiment are substantially similar to those of the aforescribed Embodiment 1, whereby there is obtained a similar effect.

Table 4 below shows the optical arrangement in the present embodiment and the aspherical surface coefficient of the f θ lens and the phase term of the diffracting optical element (BOE) 56b.

Table 4

Design Example of Scanning Optical Apparatus

| | | | | surface shape of f θ lens | |
|--|---------------------------|-------|------|---------------------------------------|----------------|
| | | | | first surface | second surface |
| wavelength used | $\lambda(\text{nm})$ | 780 | R | 6.93642e+01 | 1.98574e+02 |
| refraction index of f θ lens | n | 1.402 | Ks | -1.78054e+01 | -1.10263e+02 |
| incident angle in polygon | θ_i | -90.0 | B4s | -3.26775e-06 | -3.99337e-06 |
| max. emergence angle in polygon | θ_{max} | 45.0 | B6s | 1.09375e-09 | 8.84428e-10 |
| distance between polygon and f θ lens | e | 27.5 | B8s | -2.70818e-13 | -1.89126e-13 |
| center thickness of f θ lens | d | 7.7 | B10s | 4.17533e-17 | -1.17893e-17 |
| distance between f θ lens and scanned surface | Sk | 131.3 | Kc | -1.41847e+01 | -8.99542e+01 |
| f θ coefficient | f | 136.0 | B4e | -3.60107e-06 | -3.68241e-06 |
| polygon | $\phi 20$, 4 surfaces | | B6e | 1.39181e-09 | 6.16817e-10 |
| In the shape of f θ lens, suffix s indicates laser side, and suffix e indicates a side opposite to laser side. | | | B8e | -5.07945e-13 | -1.42807e-13 |
| | | | B10e | 1.29832e-16 | -6.18184e-19 |
| | | | | BOE Phase term (wavelength 780 nm) | |
| | | | | first surface | second surface |
| | | | C2 | - | -1.8252E-03 |
| | | | C4 | - | 4.2016E-07 |
| | | | C6 | - | -3.7548E-10 |
| | | | C8 | - | 6.8367E-14 |

Embodiment 3

In the present embodiment, the power ratio between the refracting portion 56a and the diffracting portion 56b of the scanning optical element 56 is

$$\phi L / \phi D = 1.052$$

to thereby satisfy conditional expression (1). Fig. 9 is an illustration showing curvature of image field, aberration of distortion (f θ characteristic) and image height deviation in the main scanning direction before and after temperature rise in the present embodiment, and the solid lines indicate the characteristics at room temperature (25°C), and the dotted lines indicate the characteristics when temperature has risen by 25°C and reached 50°C. From Fig. 9, it is seen that there is little or no change in focus and magnification in the main scanning direction before and after the temperature rise.

In the present embodiment, even if as described above, the material of the refracting portion (f θ lens) 56a is a material of low refractive index as compared with that in Embodiment 1, the power ratio between the refracting portion 56a

and the diffracting portion 56b is set to a suitable value so as to satisfy the aforementioned conditional expression (1), whereby as in Embodiment 1, changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of the semiconductor laser) of the scanning optical apparatus can be corrected by changes in the power of the refracting portion 56a and the diffracting portion 56b.

Fig. 10 is a cross-sectional view (main scanning cross-sectional view) of the essential portions of Embodiment 4 of the present invention in the main scanning direction. In Fig. 10, the same elements as those shown in Fig. 4 are given the same reference numerals.

The difference of the present embodiment from the aforescribed Embodiment 1 is that a diffracting optical element 74b as the diffracting portion is added to one surface of a cylindrical lens 74a for the correction of surface inclination, instead of an f θ lens. In the other points, the construction and optical action of the present embodiment are substantially similar to those of the aforescribed Embodiment 1. In such a form wherein the diffracting portion is added to the cylindrical lens, changes in the focus in the main scanning direction can be corrected, but changes in the magnification cannot be corrected. However, the size of the diffracting portion becomes small, and this leads to a reduced cost.

That is, in Fig. 10, reference numeral 74 designates an anamorphic optical element for correction of surface inclination, and this anamorphic optical element 74 has a refracting portion 74a and a diffracting portion 74b. The refracting portion 74a comprises a cylindrical lens (plano-convex lens) having no power in the main scanning direction, and the diffracting portion 74b comprises a diffracting optical element such as a binary optical element comprising the aforescribed staircase-like diffraction grating or a Fresnel-like optical element comprising a sawtooth-like diffraction grating, and the diffracting optical element 74b is added to that lens surface of the cylindrical lens 74a, which is located the light deflector 5 side. Reference numeral 76 denotes a scanning optical element having the f θ characteristic, and it comprises a single lens (f θ lens) formed of a plastic material, and the both lens surfaces of the single lens 76 in the main scanning direction are formed of an aspherical shape. Also, the single lens 76 differs in refractive power between the main scanning direction and the subscanning direction and causes a light beam based on image information deflected by the light deflector 5 to be imaged on the photosensitive drum surface 8 which is the surface to be scanned, and corrects the surface inclination of the deflecting surface of the light deflector 5.

In the present embodiment, a divergent light beam emitted from the semiconductor laser 1 is converted into a substantially parallel light beam by the collimator lens 2, and this light beam (the quantity of light) is limited by the aperture stop 3 and enters the anamorphic optical element 74 comprising the refracting portion (cylindrical lens) 74a and the diffracting portion (diffracting optical element) 74b. The light beam which has entered the anamorphic optical element 74 intactly emerges therefrom in the main scanning direction. Also, in the sub-scanning direction, the light beam converges and is imaged as a substantially linear image (a linear image long in the main scanning direction) on the deflecting surface 5a of the light deflector 5. The light beam deflected by the deflecting surface 5a of the light deflector 5 is directed onto the photosensitive drum surface 8 through the f θ lens 76 differing in refractive power between the main scanning direction and the sub-scanning direction, and the light deflector 5 is rotated in the direction of arrow A, whereby the light beam scans on the photosensitive drum surface 8 in the direction of arrow B. Thereby, image recording is effected on the photosensitive drum surface 8 which is a recording medium.

Table 5 below shows the optical arrangement in the present embodiment, the aspherical surface coefficient of the f θ lens and the phase term of the diffracting optical element (BOE).

Table 5

Design Example of Scanning Optical Apparatus

| | | | | surface shape of f θ lens | |
|--|---------------------------|-------|---------------------------------------|----------------------------------|----------------|
| | | | | first surface | second surface |
| wavelength used | $\lambda(\text{nm})$ | 780 | R | 5.35941e+01 | 2.04585e+02 |
| refractive index of f θ lens | n | 1.525 | Ks | -1.85041e+01 | -3.19655e+02 |
| incident angle in polygon | θ_i | -90.0 | B4s | -4.01467e-06 | -5.67674e-06 |
| max. emergence angle in polygon | θ_{max} | 45.0 | B6s | 1.97617e-10 | 1.13298e-09 |
| distance between polygon and f θ lens | l | 28.9 | B8s | 3.18251e-13 | -1.08244e-12 |
| distance between cylinder and polygon | e | 21.3 | B10s | -4.34340e-17 | 3.75204e-17 |
| center thickness of f θ lens | d | 8.0 | Ke | -1.85041e+01 | -3.19655e+02 |
| distance between f θ lens and scanned surface | Sk | 128.2 | B4e | -6.38051e-06 | -7.32456e-06 |
| f θ coefficient | f | 136.0 | B6e | -5.04862e-10 | 4.21805e-10 |
| polygon | $\phi 20$, 4 surfaces | | B8e | 2.89411e-13 | -1.75629e-12 |
| In the shape of f θ lens, suffix s indicates laser side, and suffix e indicates a side opposite to laser side. | | | B10e | 1.05151e-15 | 5.30015e-17 |
| | | | BOE Phase term (wavelength 780 nm) | | |
| | | | cylinder second surfaces | | |
| | | | C2 | -2.6857E-03 | - |
| | | | C4 | - | - |
| | | | C6 | - | - |
| | | | C8 | - | - |

Embodiment 4

Fig. 11 is an illustration showing curvature of image field, aberration of distortion and image height deviation in the main scanning direction before and after temperature rise in the present embodiment, and the solid lines indicate the characteristics at room temperature (25°C) and the dotted lines indicate the characteristics when temperature has risen by 25°C and reached 50°C. It is seen from Fig. 11 that there is little or no change in the focus in the main scanning direction before and after the temperature rise.

In the present embodiment, as described above, the diffracting optical element 74b as the diffracting portion is added to one surface of the cylindrical lens 74a, whereby changes in the focus in the main scanning direction resulting from the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of the semiconductor laser) of the scanning optical apparatus are corrected by changes in the power of the diffracting portion 74b and the f θ lens 76 as the refracting portion. Also, in the present embodiment, the diffracting optical element is added to one surface of

not the $f\theta$ lens (scanning optical element) but the cylindrical lens, whereby the effect can be realized by an easier construction as compared with the aforescribed Embodiments 1 to 3.

Embodiment 5 of the present invention will now be described with reference to Fig. 12. The difference of this embodiment from the aforescribed Embodiment 4 is that a diffracting optical element 32b as the diffracting portion is added to one surface of a collimator lens 32a. In the other points, the construction and optical action of this embodiment are substantially similar to those of the aforescribed Embodiment 4, whereby there is obtained a similar effect.

That is, in the present embodiment, a converting optical element 32 is comprised of the collimator lens 32a as the refracting portion, and the diffracting optical element 32b as the diffracting portion, and the diffracting optical element is added to one of the both lens surfaces of the collimator lens, whereby as in the aforescribed Embodiment 4, changes in the focus in the main scanning direction resulting from the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of the semiconductor laser) of the scanning optical apparatus are corrected by changes in the power of the diffracting portion 32b and the $f\theta$ lens 76 as the refracting portion.

While in each embodiment, the diffracting optical element is added to one surface of one of a plurality of optical elements constituting an optical system, this is not restrictive, but the present invention can obtain an effect similar to that of each of the above-described embodiments even if the diffracting optical element is independently disposed in the optical path.

According to the present invention, there can be achieved a scanning optical apparatus in which as previously described, changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of optical means having a refracting portion and a diffracting portion, whereby which is strong against the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of a semiconductor laser which is light source means) and moreover is suitable for highly minute printing and compact.

Also, according to the present invention, there can be achieved a scanning optical apparatus in which as previously described, changes in the focus and magnification in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of a scanning optical element having a refracting portion and a diffracting portion, whereby which is strong against the environmental fluctuations (temperature fluctuation and the wavelength fluctuation of a semiconductor laser which is light source means) and moreover is suitable for highly minute printing and compact.

A scanning optical apparatus includes a semiconductor laser as a light source, a deflector for deflecting a light beam emitted from the semiconductor laser, and optical element for directing the light beam emitted from the semiconductor laser to a surface to be scanned. The optical element includes a refracting portion and a diffracting portion, wherein changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the optical element.

Claims

1. A scanning optical apparatus comprising:

light source means comprising a semiconductor laser;
a deflecting element for deflecting a light beam emitted from said light source means; and
optical means for directing the light beam emitted from said light source means onto a surface to be scanned, said optical means having a refracting portion and a diffracting portion;
wherein changes in the focus in the main scanning direction resulting from the environmental fluctuations of said scanning optical apparatus are corrected by the characteristic of said optical means.

2. A scanning optical apparatus according to Claim 1, wherein said environmental fluctuations are temperature fluctuation and the wavelength fluctuation of said semiconductor laser.

3. A scanning optical apparatus according to Claim 1, wherein said characteristic is the power ratio between the refracting portion and the diffracting portion of said optical means.

4. A scanning optical apparatus according to Claim 1, wherein said optical means is a scanning optical element for directing the light beam deflected by said deflecting element onto the surface to be scanned, and changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations of said scanning optical apparatus are corrected by the characteristic of said scanning optical element.

5. A scanning optical apparatus according to Claim 4, wherein when the powers of the refracting portion and the diffracting portion of said scanning optical element are ϕL and ϕD , respectively, the condition that

$$1.0 \leq \phi L / \phi D \leq 2.6$$

is satisfied.

- 5 6. A scanning optical apparatus according to Claim 4, wherein said refracting portion comprises a single lens, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said single lens.
7. A scanning optical apparatus according to Claim 6, wherein the material of said single lens is a plastic material.
- 10 8. A scanning optical apparatus according to Claim 6, wherein the both lens surfaces of said single lens in the main scanning direction comprise an aspherical shape.
9. An scanning optical apparatus according to Claim 6, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.
- 15 10. A scanning optical apparatus according to Claim 6, wherein said diffracting optical element is a binary optical element comprising a staircase-like diffraction grating.
- 20 11. A scanning optical apparatus according to Claim 6, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.
12. A scanning optical apparatus according to Claim 5, wherein the power ratio between the refracting portion and the diffracting portion of said scanning optical element satisfies said condition within the range from the on-axis to the off-axis.
- 25 13. A scanning optical apparatus according to Claim 1, wherein said optical means comprises an anamorphic optical element having a diffracting portion and for causing the light beam emitted from said light source means to be imaged in a linear shape long in the main scanning direction on the deflecting surface of said deflecting element, and a scanning optical element having a refracting portion for directing the light beam deflected by said deflecting element onto the surface to be scanned, and changes in the focus in the main scanning direction resulting from the environmental fluctuations of said scanning optical apparatus are corrected by the characteristic of said anamorphic optical element and said scanning optical element.
- 30 14. A scanning optical apparatus according to Claim 13, wherein said characteristic is the power ratio between the diffracting portion of said anamorphic optical element and the refracting portion of said scanning optical element.
- 35 15. A scanning optical apparatus according to Claim 13, wherein said anamorphic optical element includes a cylindrical lens, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said cylindrical lens.
- 40 16. A scanning optical apparatus according to Claim 13, wherein said scanning optical element is a single lens, and the material of said single lens is a plastic material.
- 45 17. A scanning optical apparatus according to Claim 16, wherein the both lens surfaces of said single lens in the main scanning direction comprises an aspherical shape.
18. A scanning optical apparatus according to Claim 16, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.
- 50 19. A scanning optical apparatus according to Claim 15, wherein said diffraction optical element is a binary optical element comprising a staircase-like diffraction grating.
20. A scanning optical apparatus according to Claim 15, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.
- 55 21. A scanning optical apparatus according to Claim 1, wherein said optical means comprises a converting optical element having a diffracting portion and for converting the light beam emitted from said light source means into a sub-

stantially parallel light beam, and a scanning optical element having a refracting portion for directing the light beam deflected by said deflecting element onto the surface to be scanned, and changes in the focus in the main scanning direction resulting from the environmental fluctuations of said scanning optical apparatus are corrected by the characteristic of said converting optical element and said scanning optical element.

22. A scanning optical apparatus according to Claim 21, wherein said characteristic is the power ratio between the diffracting portion of said converting optical element and the refracting portion of said scanning optical element.

23. A scanning optical apparatus according to Claim 21, wherein said converting optical element includes a collimator lens having positive refractive power, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said collimator lens.

24. A scanning optical apparatus according to Claim 21, wherein said scanning optical element is a single lens, and the material of said single lens is a plastic material.

25. A scanning optical apparatus according to Claim 24, wherein the both lens surfaces of said single lens in the main scanning direction comprises an aspherical shape.

26. A scanning optical apparatus according to Claim 24, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.

27. A scanning optical apparatus according to Claim 23, wherein said diffracting optical element is a binary optical element comprising a staircase-like diffraction grating.

28. A scanning optical apparatus according to Claim 23, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.

29. A laser beam printer apparatus comprising:

light source means comprising a semiconductor laser;
a deflecting element for deflecting a light beam emitted from said light source means;
a recording medium; and
optical means for directing the light beam emitted from said light source means onto the surface of said recording medium, said optical means having a refracting portion and a diffracting portion;
wherein changes in the focus in the main scanning direction resulting from the environmental fluctuations of said apparatus are corrected by the characteristic of said optical means.

30. A laser beam printer apparatus according to Claim 29, wherein said environmental fluctuations are temperature fluctuation and the wavelength fluctuation of said semiconductor laser.

31. A laser beam printer apparatus according to Claim 29, wherein said characteristic is the power ratio between the refracting portion and the diffracting portion of said optical means.

32. A laser beam printer apparatus according to Claim 29, wherein said optical means is a scanning optical element for directing the light beam deflected by said deflecting element onto a surface to be scanned, and changes in the magnification and focus in the main scanning direction resulting from the environmental fluctuations of said apparatus are corrected by the characteristic of said scanning optical element.

33. A laser beam printer apparatus according to Claim 32, wherein when the powers of the refracting portion and the diffracting portion of said scanning optical element are ϕL and ϕD , respectively, the condition that

$$1.0 \leq \phi L / \phi D \leq 2.6$$

is satisfied.

34. A laser beam printer apparatus according to Claim 32, wherein said refracting portion comprises a single lens, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said single lens.

35. A laser beam printer apparatus according to Claim 34, wherein the material of said single lens is a plastic material.
36. A laser beam printer apparatus according to Claim 34, wherein the both lens surfaces of said single lens in the main scanning direction comprise an aspherical shape.
- 5 37. A laser beam printer apparatus according to Claim 34, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.
- 10 38. A laser beam printer apparatus according to Claim 34, wherein said diffracting optical element is a binary optical element comprising a staircase-like diffraction grating.
39. A laser beam printer apparatus according to Claim 34, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.
- 15 40. A laser beam printer apparatus according to Claim 33, wherein the power ratio between the refracting portion and the diffracting portion of said scanning optical element satisfies said condition within the range from the on-axis to the off-axis.
- 20 41. A laser beam printer apparatus according to Claim 29, wherein said optical means comprises an anamorphic optical element having a diffracting portion and for causing the light beam emitted from said light source means to be imaged in a linear shape long in the main scanning direction on the deflecting surface of said deflecting element, and a scanning optical element having a refracting portion for directing the light beam deflected by said deflecting element onto the surface to be scanned, and changes in the focus in the main scanning direction resulting from the environmental fluctuations of said apparatus are corrected by the characteristic of said anamorphic optical element and said scanning optical element.
- 25 42. A laser beam printer apparatus according to Claim 41, wherein said characteristic is the power ratio between the diffracting portion of said anamorphic optical element and the refracting portion of said scanning optical element.
- 30 43. A laser beam printer apparatus according to Claim 41, wherein said anamorphic optical element includes a cylindrical lens, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said cylindrical lens.
- 35 44. A laser beam printer apparatus according to Claim 41, wherein said scanning optical element is a single lens, and the material of said single lens is a plastic material.
- 45 45. A laser beam printer apparatus according to Claim 44, wherein the both lens surfaces of said single lens in the main scanning direction comprise an aspherical shape.
- 40 46. A laser beam printer apparatus according to Claim 44, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.
47. A laser beam printer apparatus according to Claim 43, wherein said diffracting optical element is a binary optical element comprising a staircase-like diffraction grating.
- 45 48. A laser beam printer apparatus according to Claim 43, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.
- 50 49. A laser beam printer apparatus according to Claim 29, wherein said optical means comprises a converting optical element having a diffracting portion and for converting the light beam emitted from said light source means into a substantially parallel light beam, and a scanning optical element having a refracting portion for directing the light beam deflected by said deflecting element onto the surface to be scanned, and changes in the focus in the main scanning direction resulting from the environmental fluctuations of said apparatus are corrected by the characteristic of said converting optical element and said scanning optical element.
- 55 50. A laser beam printer apparatus according to Claim 49, wherein said characteristic is the power ratio between the diffracting portion of said converting optical element and the refracting portion of said scanning optical element.

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51. A laser beam printer apparatus according to Claim 49, wherein said converting optical element includes a collimator lens having positive refractive power, said diffracting portion comprises a diffracting optical element, and said diffracting optical element is added to at least one of the both lens surfaces of said collimator lens.

5 **52.** A laser beam printer apparatus according to Claim 49, wherein said scanning optical element is a single lens, and the material of said single lens is a plastic material.

53. A laser beam printer apparatus according to Claim 52, wherein the both lens surfaces of said single lens in the main scanning direction comprise an aspherical shape.

10 **54.** A laser beam printer apparatus according to Claim 52, wherein said single lens differs in refractive power between the main scanning direction and the sub-scanning direction.

15 **55.** A laser beam printer apparatus according to Claim 51, wherein said diffracting optical element is a binary optical element comprising a staircase-like diffraction grating.

56. A laser beam printer apparatus according to Claim 51, wherein said diffracting optical element is a Fresnel-like optical element comprising a sawtooth-like diffraction grating.

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FIG. 1

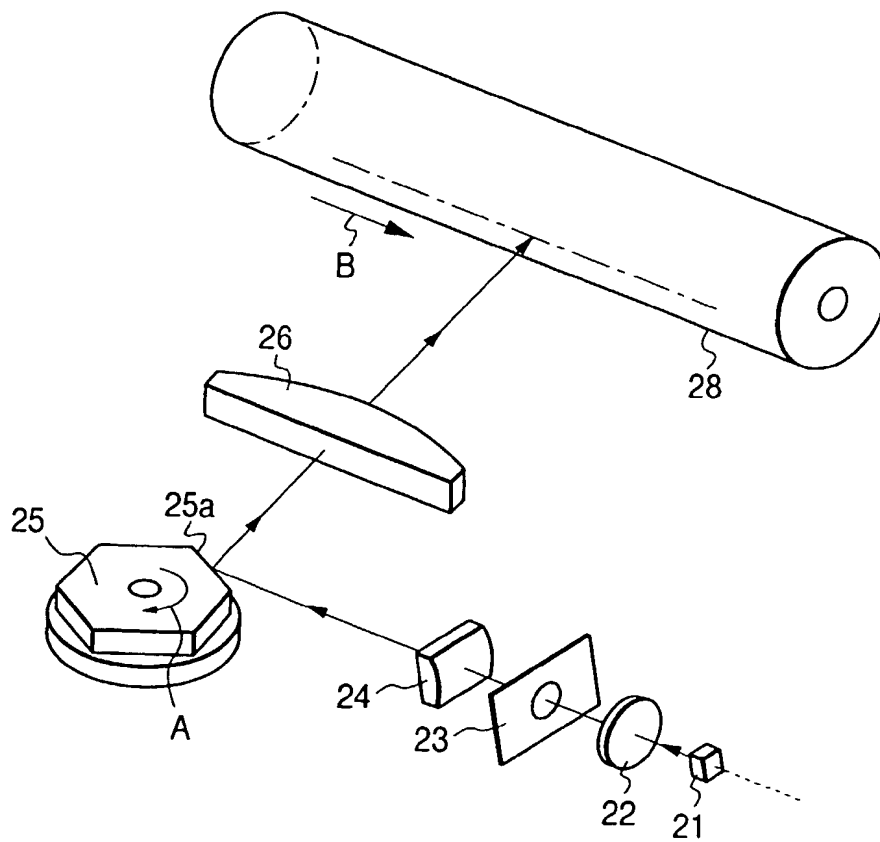


FIG. 2

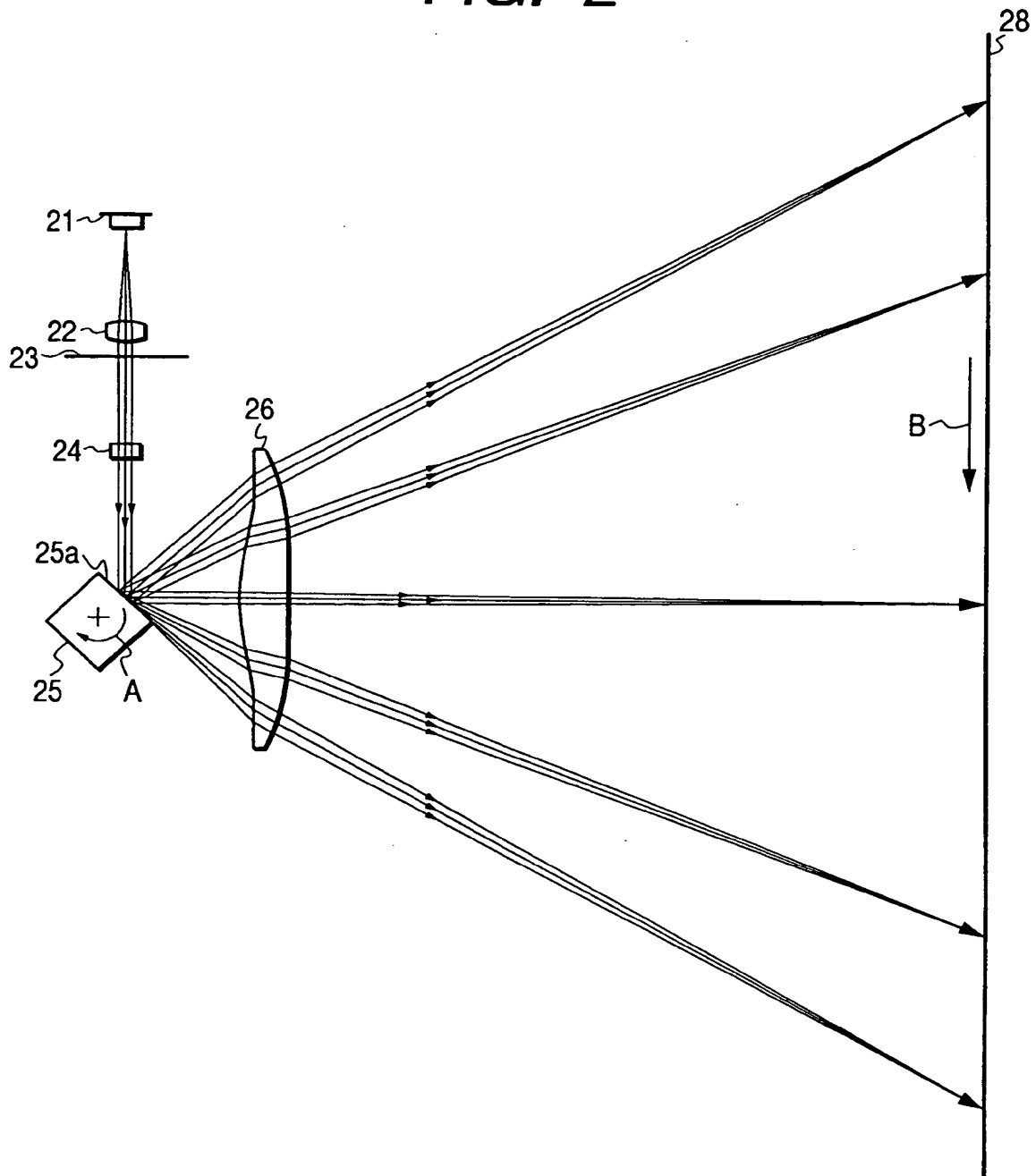


FIG. 3

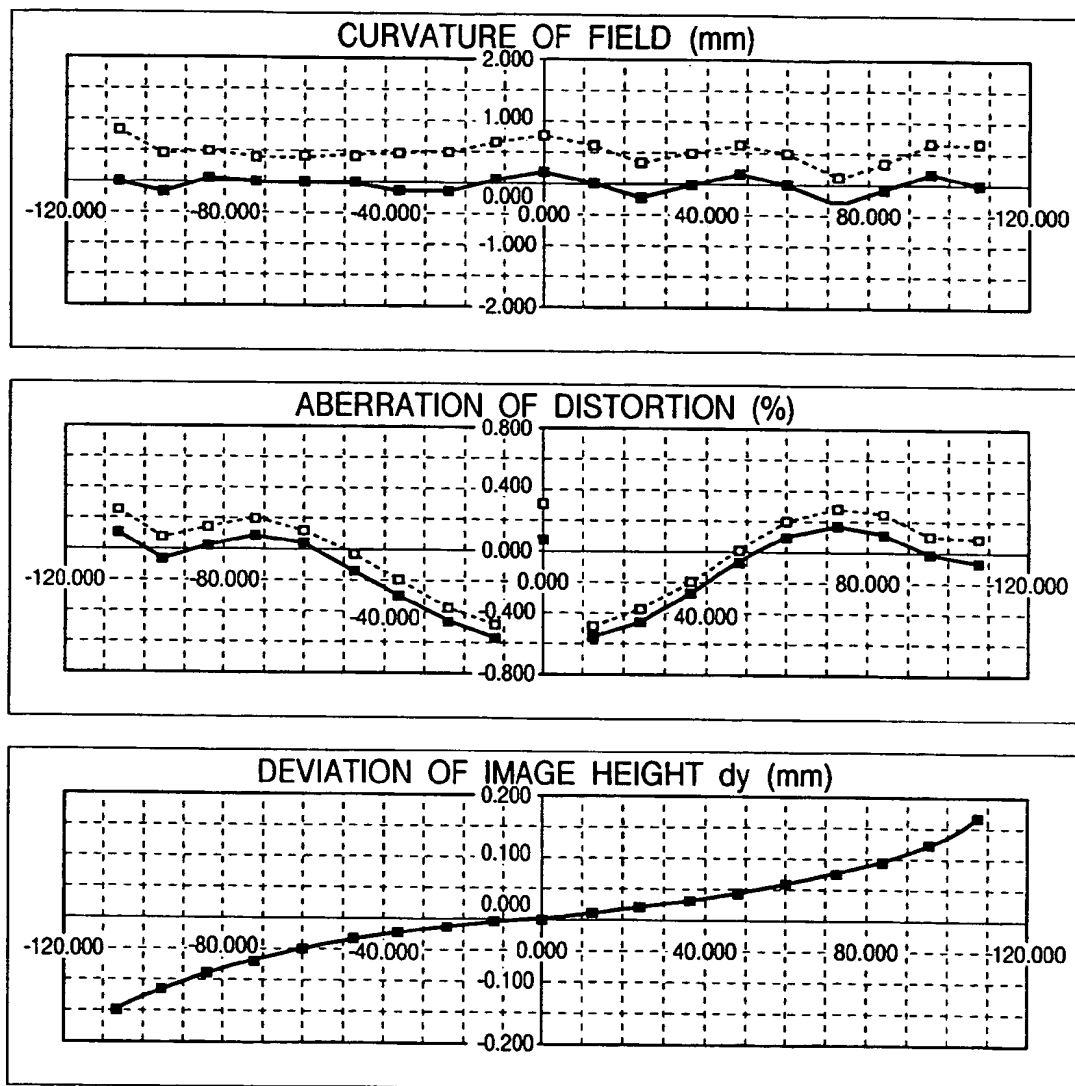


FIG. 4

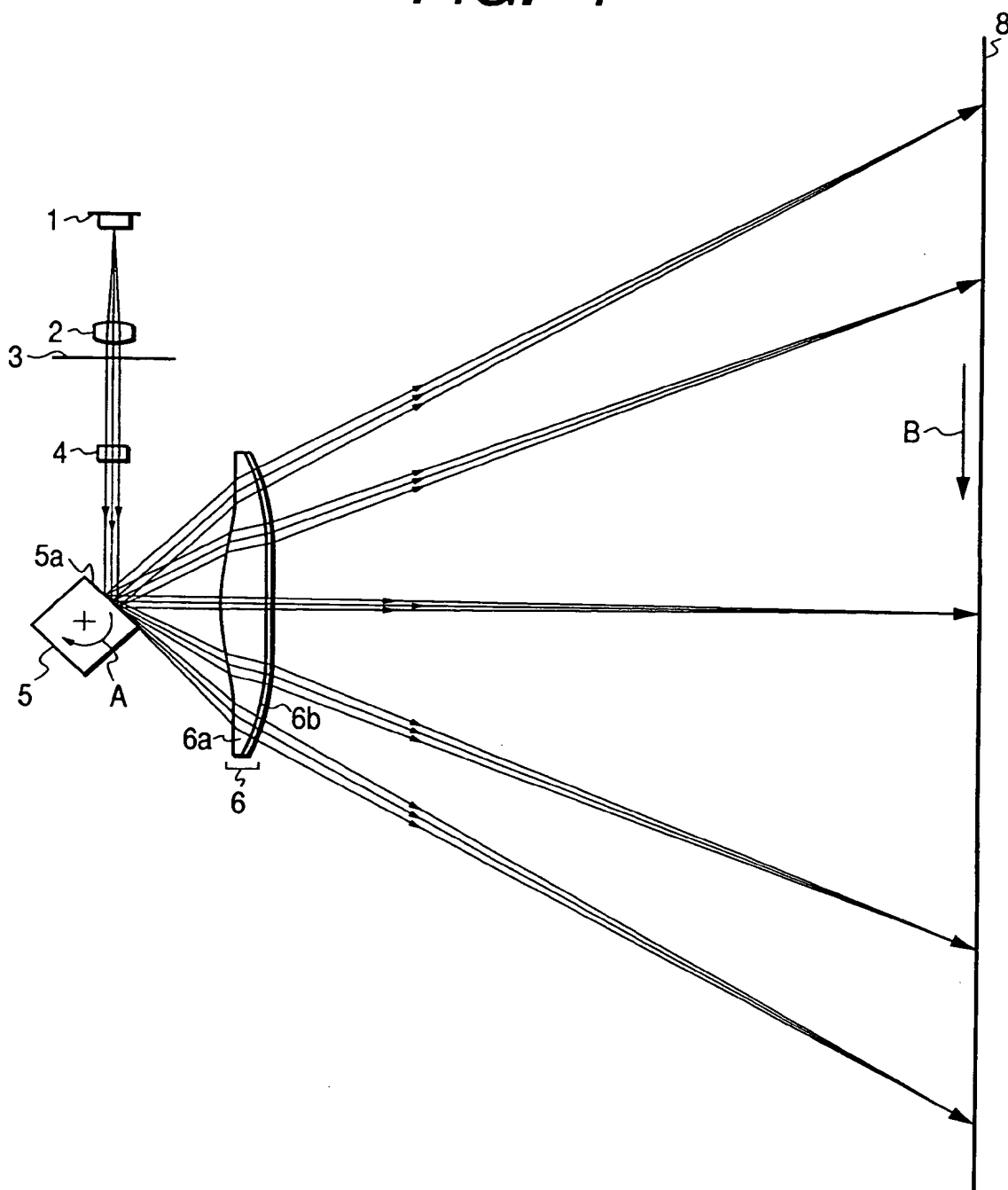


FIG. 5

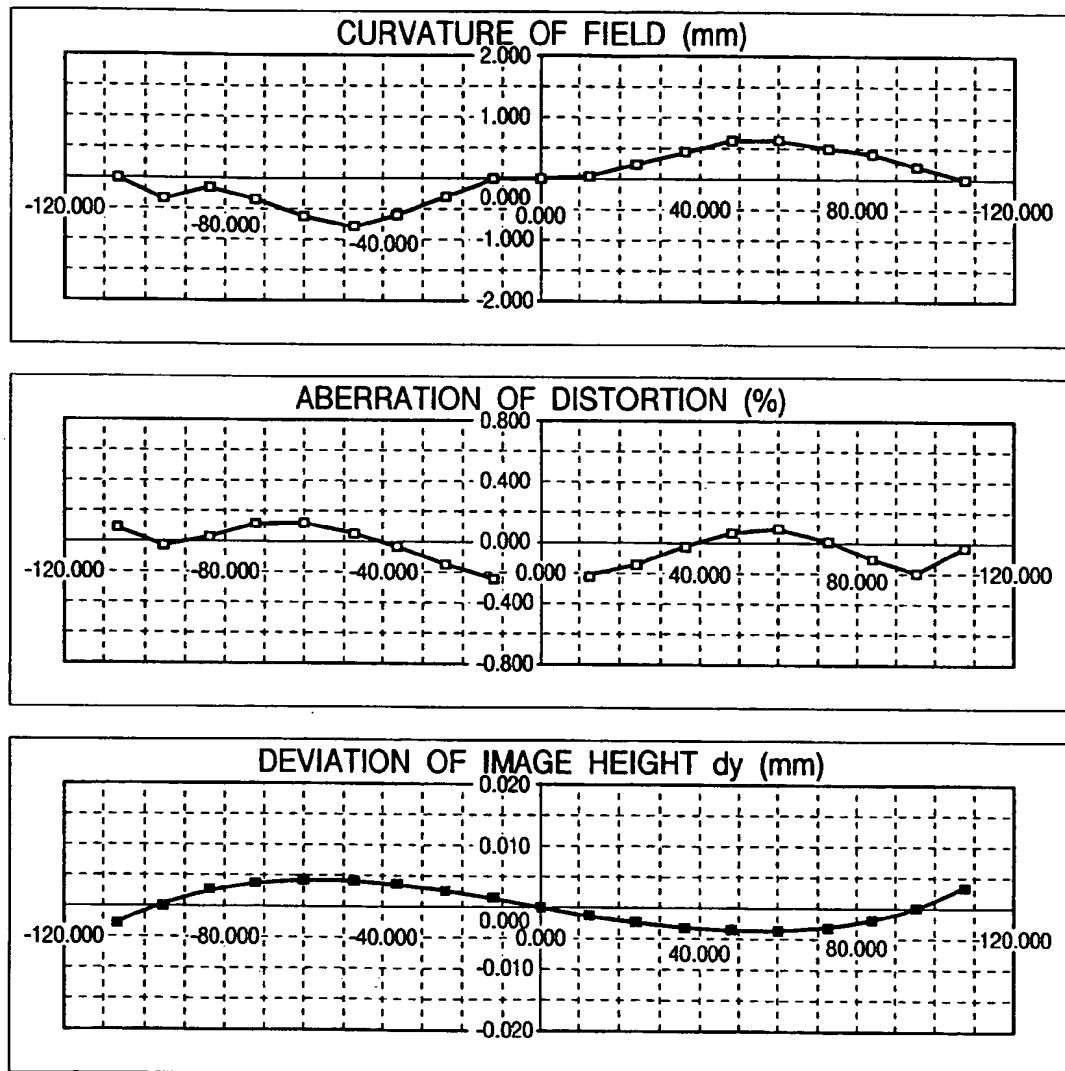


FIG. 6

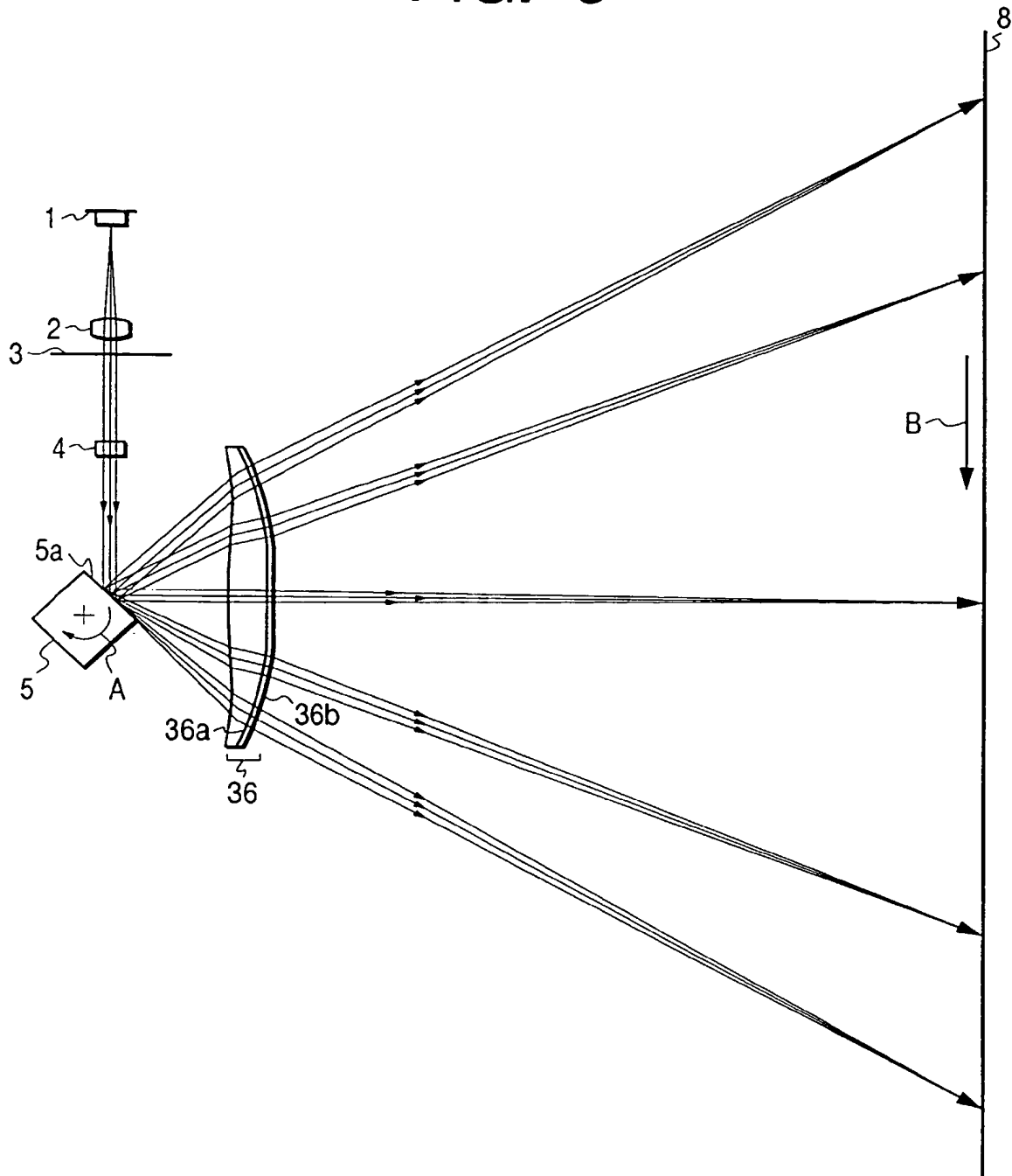


FIG. 7

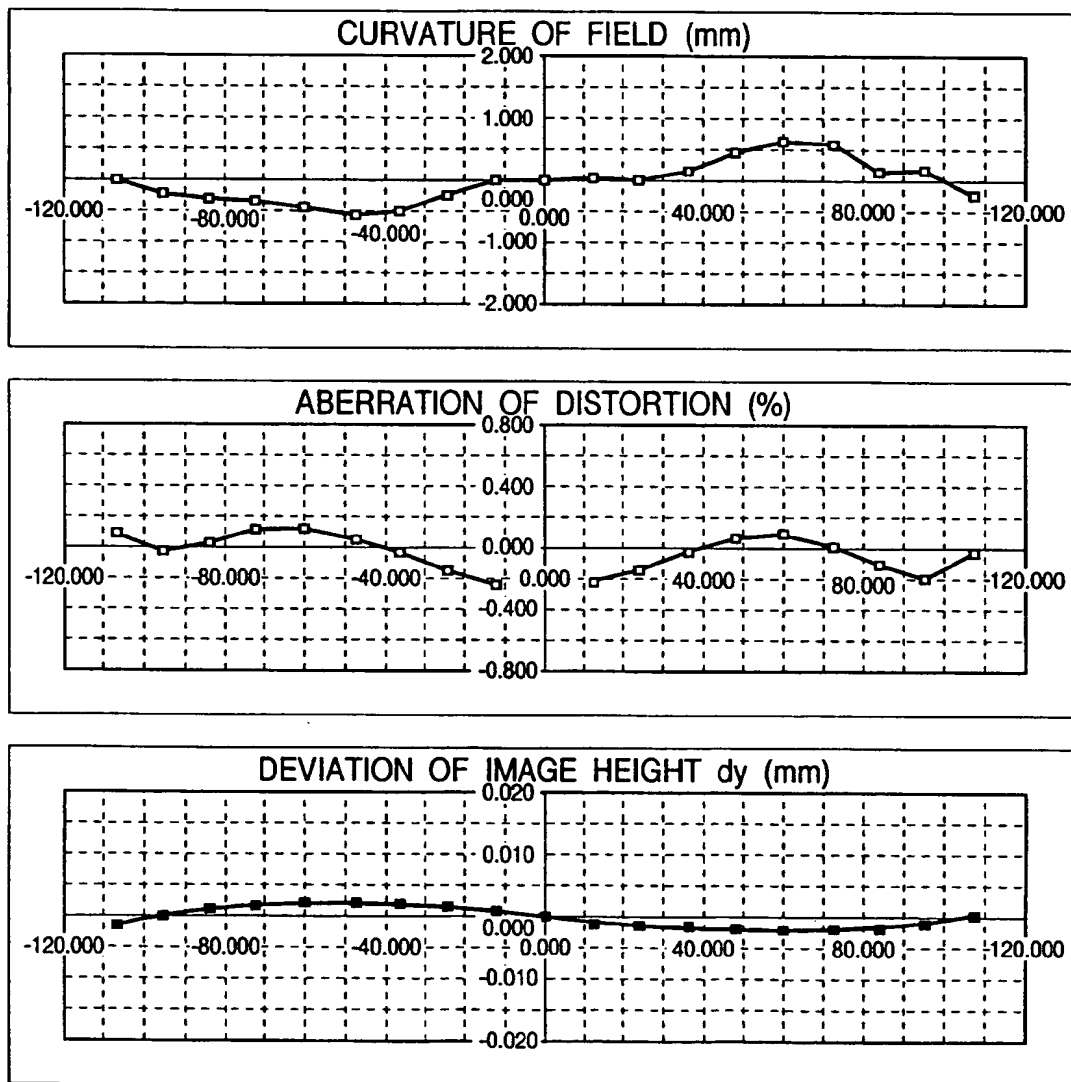


FIG. 8

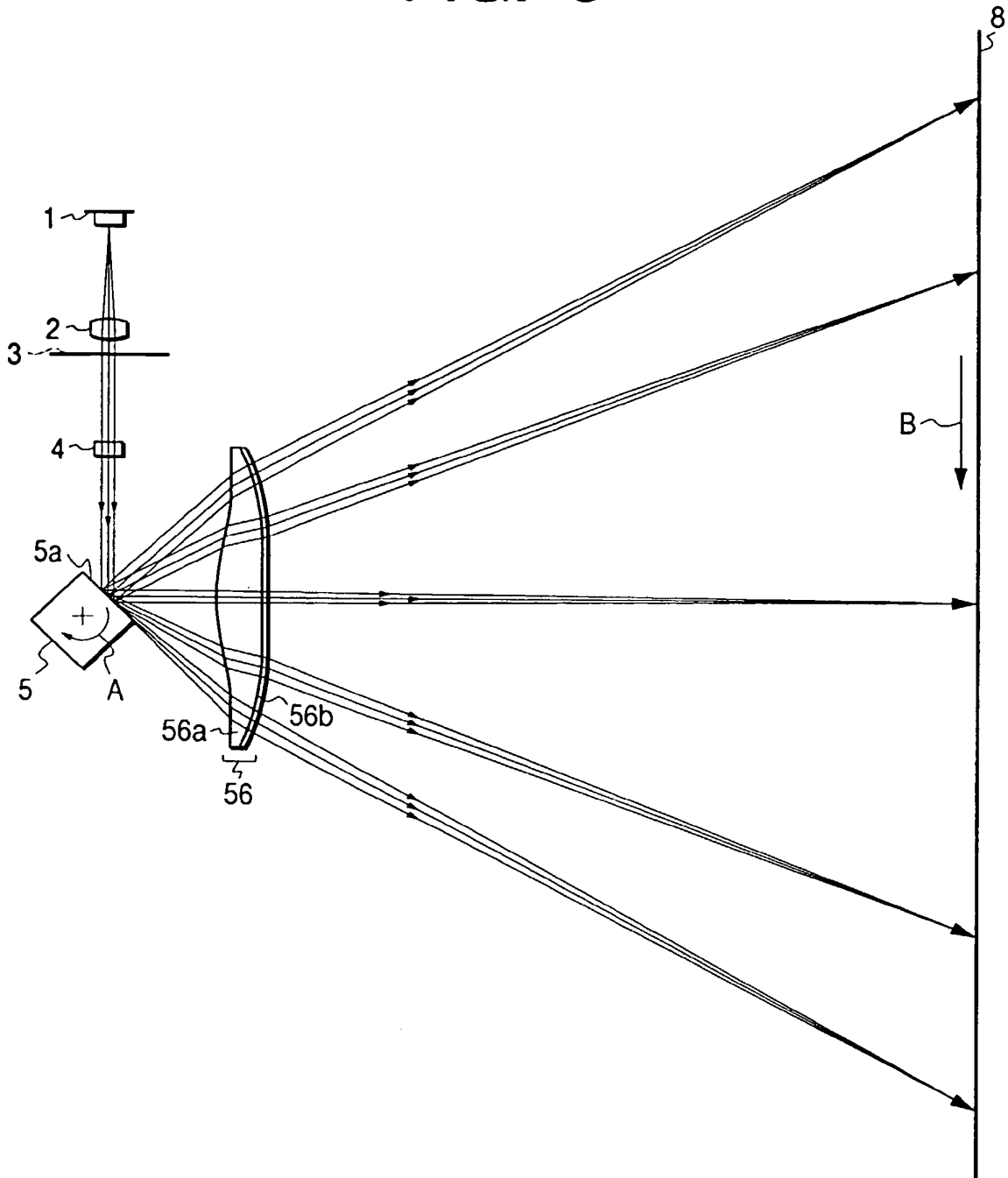


FIG. 9

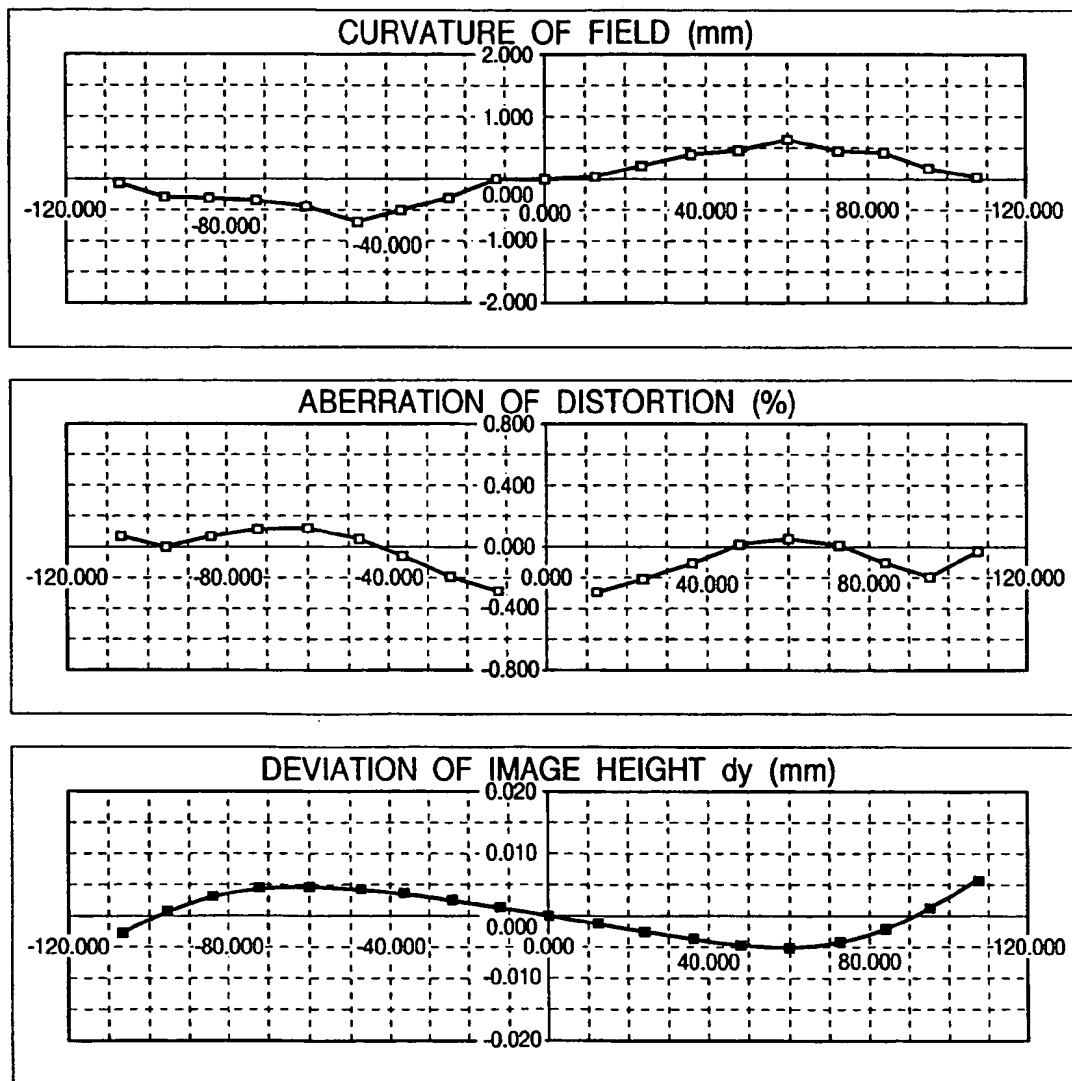


FIG. 10

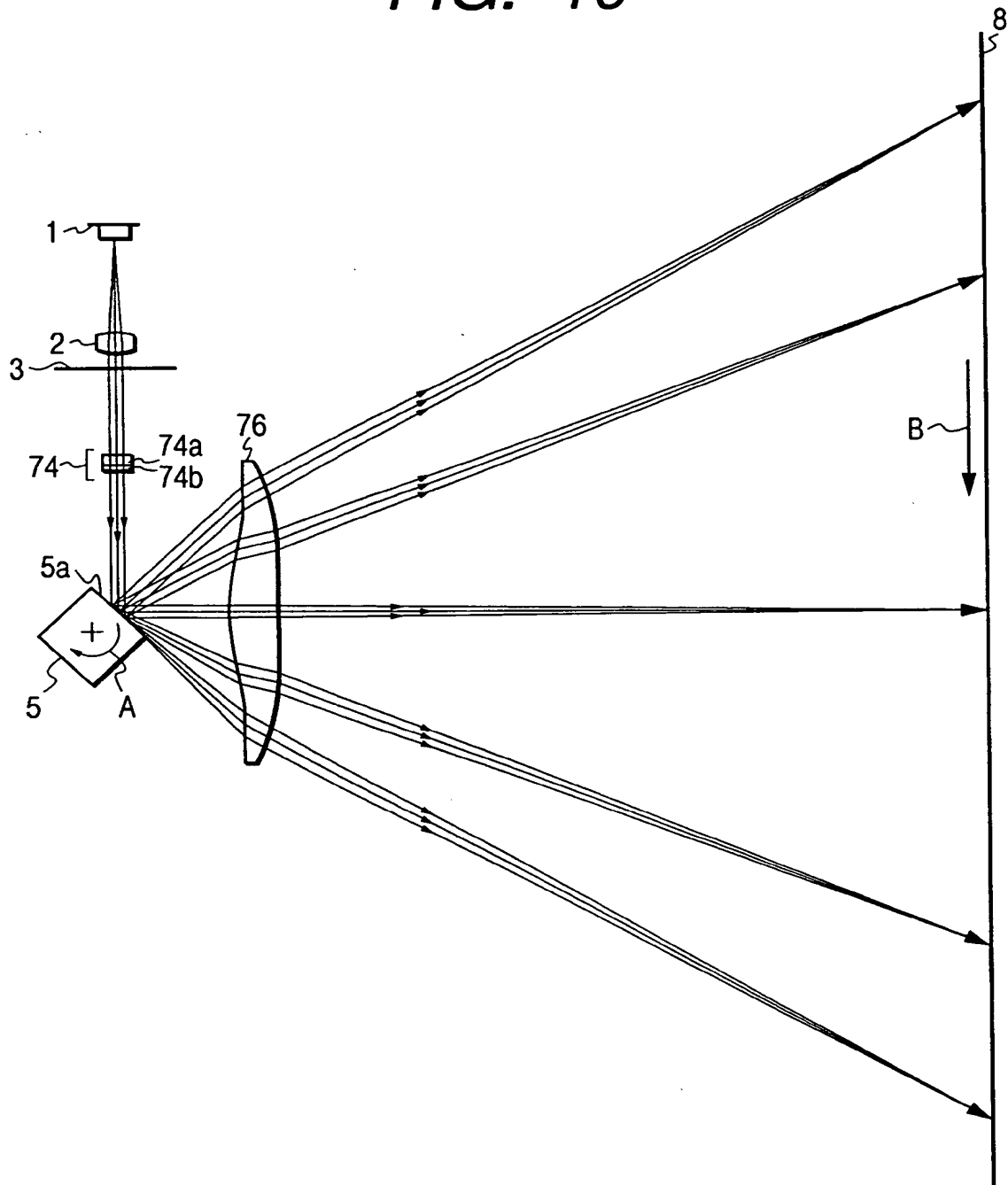


FIG. 11

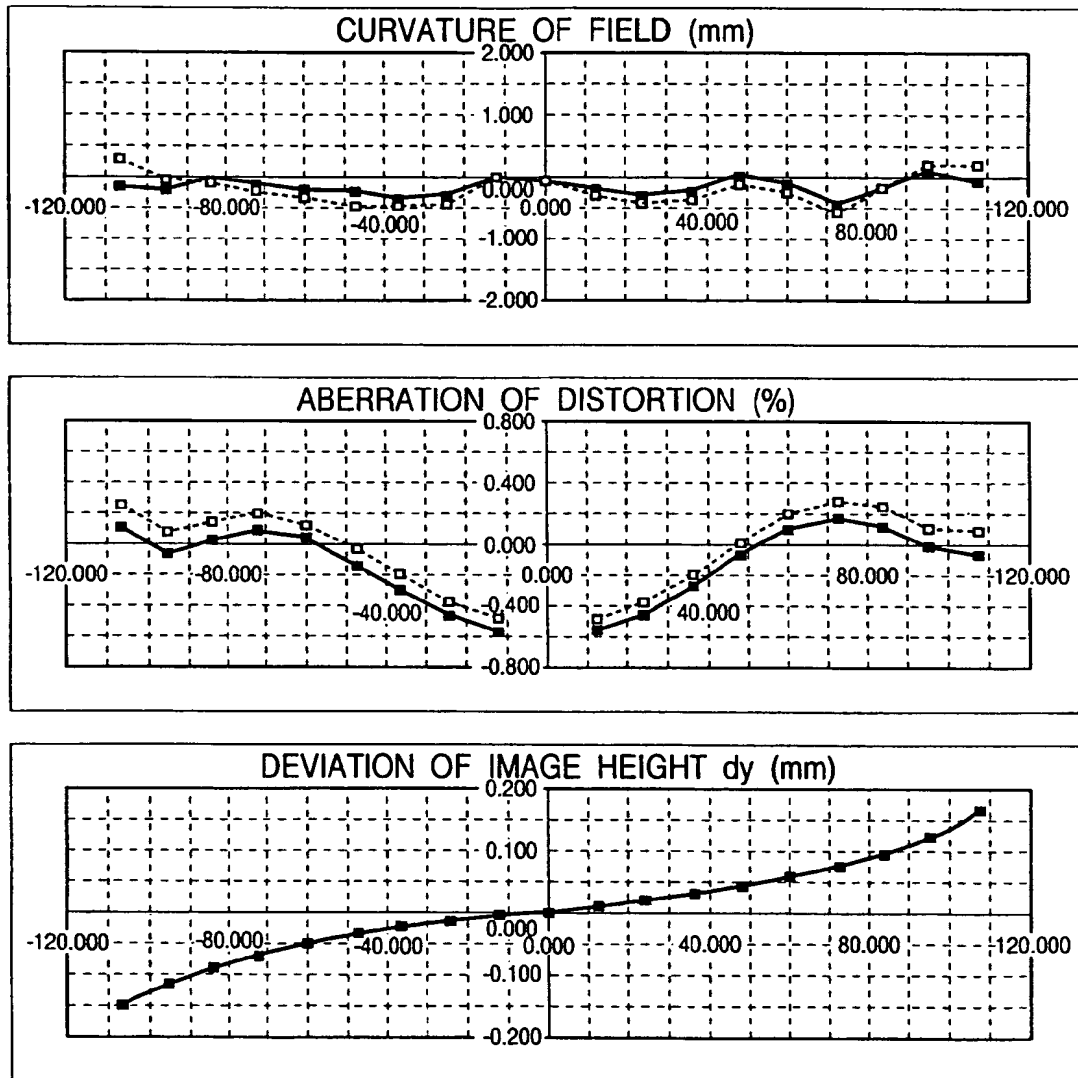
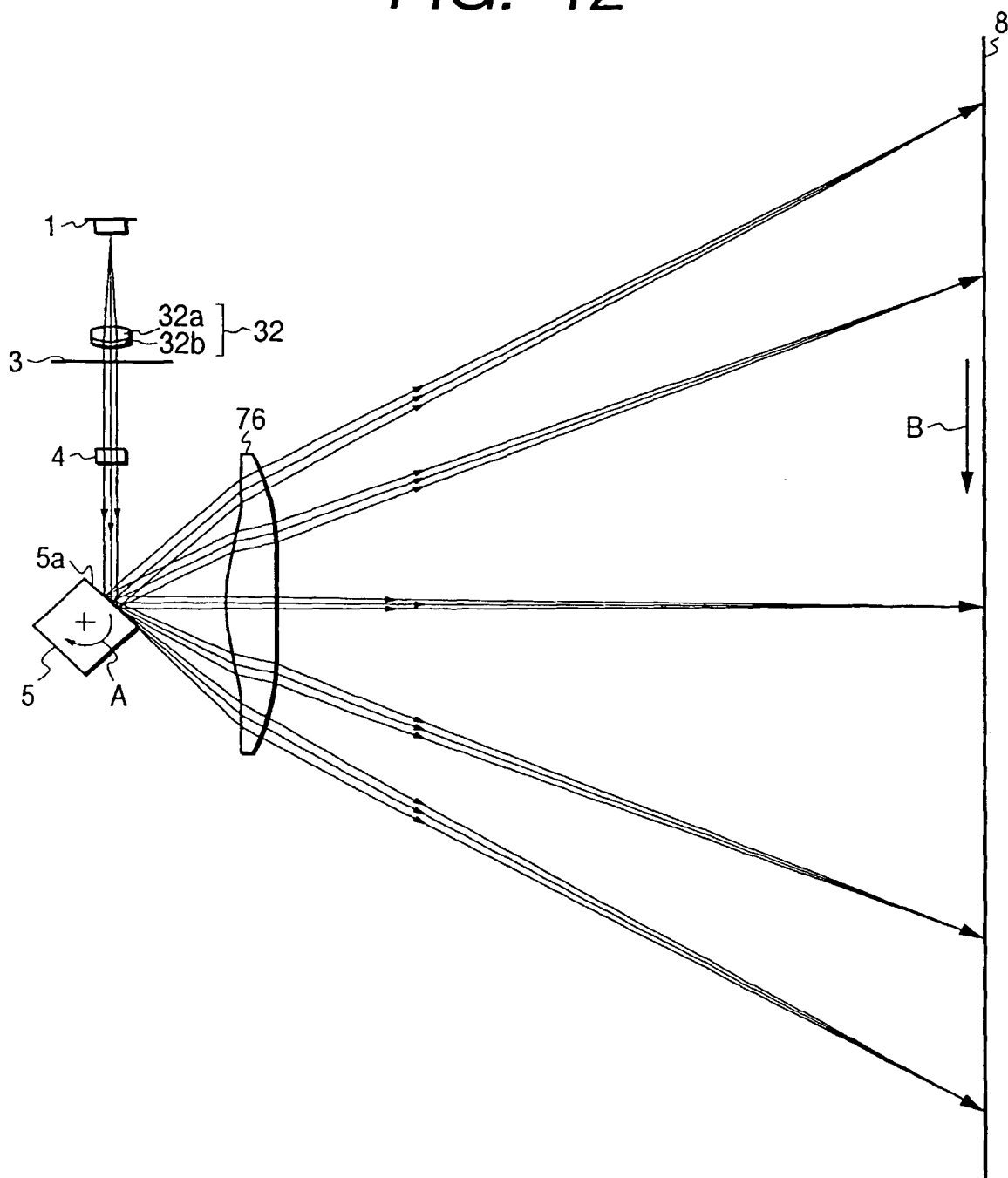
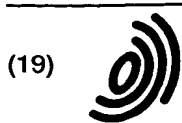


FIG. 12





(19)

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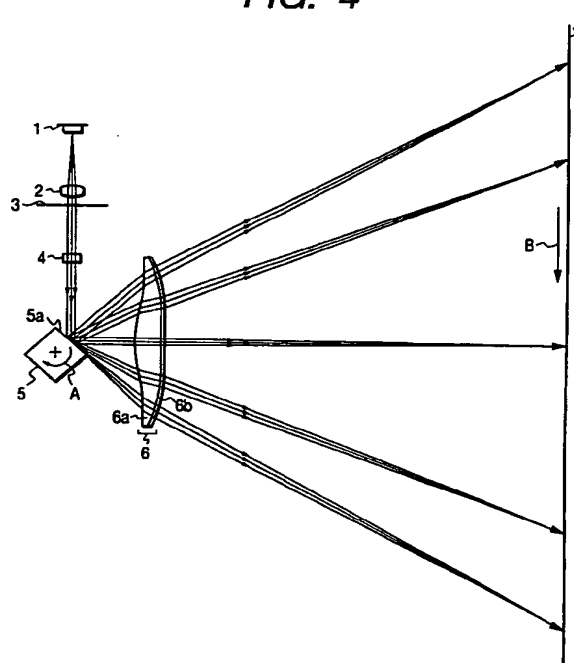
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Tokyo (JP)

(54) Corrected scanning optical apparatus

(57) A scanning optical apparatus includes a semiconductor laser (1) as a light source, a deflector (5) for deflecting a light beam emitted from the semiconductor laser, and optical element (6) for directing the light beam emitted from the semiconductor laser to a surface (8) to be scanned. The optical element (6) includes a refracting portion (6a) and a diffracting portion (6b), wherein changes in the focus in the main scanning direction resulting from the environmental fluctuations of the scanning optical apparatus are corrected by the characteristic of the optical element.

FIG. 4



EP 0 827 004 A3



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Application Number
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